



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kiyoshi MOTEKI &
Satoru OSHIKAWA

GAU: 2851

Examiner:

Atty. Docket No. 25,096-USA

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U.S. Application No. 09/856,384

Filing Date: May 21, 2001

For: Optical Apparatus, Exposure Apparatus,
Laser Light Source, Gas Supply Method,
Exposure Method, and Device Manufacturing
Method

Commissioner for Patents
Washington, D.C. 20231

SECOND PRELIMINARY AMENDMENT

Sir:

Please amend the application as set forth below.

In The Specification

On page 1, please delete the title and replace it with the following:

--Optical Apparatus, Exposure Apparatus, Laser Light Source, Gas Supply
Method, Exposure Method, and Device Manufacturing Method--.

Respectfully submitted,



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